CAD for **MFMS**

Computer-Aided Design for Micro-Electro-Mechanical Systems Eigenvalues, Energy Losses, and Dick Tracy Watches

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UC Davis. 9 Mar 2006



The Computational Science Picture

CAD for MEMS

Resonal MEMS

HiQLa

Losses

Resonato Analysis

Conclusion

- Application modeling
 - Checkerboard resonator
 - Disk resonator
 - Shear ring resonator
- Mathematical analysis
 - Physical modeling and finite element technology
 - Structured eigenproblems and reduced-order models
 - Parameter-dependent eigenproblems
- Software engineering
 - HiQLab
 - SUGAR
 - FEAPMEX

The Computational Science Picture

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Outline

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Conclusions

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Resonant MEMS

- 2 HiQLab
- 3 Anchor Losses
- 4 Disk Resonator Analysis

Outline

CAD for **MEMS**

Resonant **MEMS**

- **Resonant MEMS**
- HiQLab
- **Anchor Losses**
- Disk Resonator Analysis

What are MEMS?

CAD for MEMS

Resonant MEMS MEMS Basics

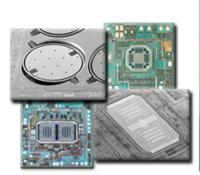
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Checkerboard Mo

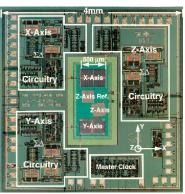
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Conclusion





MEMS Basics

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Resonant MEMS MEMS Basics RF MEMS Checkerboard Mod

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Conclusions

Contolacione

- Micro-Electro-Mechanical Systems
 - Chemical, fluid, thermal, optical (MECFTOMS?)
- Applications:
 - Sensors (inertial, chemical, pressure)
 - Ink jet printers, biolab chips
 - Radio devices: cell phones, inventory tags, pico radio
- Use integrated circuit (IC) fabrication technology
- Tiny, but still classical physics

Radio-Frequency MEMS

CAD for MEMS

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RF MEMS
Checkerboard N

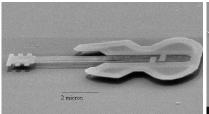
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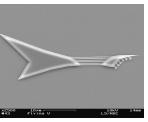
Losse

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Conclusions

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Microguitars from Cornell University (1997 and 2003)

- MHz-GHz mechanical resonators
- Impact: smaller, lower-power cell phones
- Other uses:
 - Sensing elements (e.g. chemical sensors)
 - Really high-pitch guitars

Micromechanical Filters

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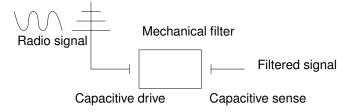
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Conclusion



- Mechanical high-frequency (high MHz-GHz) filter
 - Your cell phone is mechanical!
 - New MEMS filters can be integrated with circuitry
 - ⇒ smaller and lower power

Ultimate Success

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"Calling Dick Tracy!"



Designing Transfer Functions

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RE MEMS

Time domain:

$$Mu'' + Cu' + Ku = b\phi(t)$$
$$y(t) = \rho^{T}u$$

Frequency domain:

$$-\omega^{2}M\hat{u} + i\omega C\hat{u} + K\hat{u} = b\hat{\phi}(\omega)$$
$$\hat{y}(\omega) = p^{T}\hat{u}$$

Transfer function:

$$H(\omega) = \rho^{T}(-\omega^{2}M + i\omega C + K)^{-1}b$$

$$\hat{y}(\omega) = H(\omega)\hat{\phi}(\omega)$$

Narrowband Filter Needs

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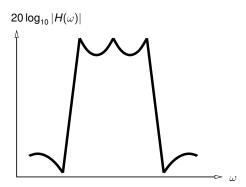
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- Want "sharp" poles for narrowband filters
- ⇒ Want to minimize damping



Checkerboard Resonator

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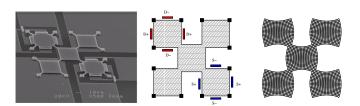
Checkerboard Model

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Conclusion



- Anchored at outside corners
- Excited at northwest corner
- Sensed at southeast corner
- Surfaces move only a few nanometers

Checkerboard Model Reduction

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Anchor

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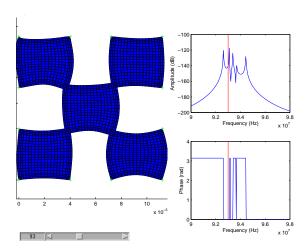
Conclusions

- Finite element model: *N* = 2154
 - Expensive to solve for every $H(\omega)$ evaluation!
- Build a reduced-order model to approximate behavior
 - Reduced system of 80 to 100 vectors
 - Evaluate $H(\omega)$ in milliseconds instead of seconds
 - Without damping: standard Arnoldi projection
 - With damping: Second-Order ARnoldi (SOAR)

Checkerboard Simulation

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Checkerboard Model



Checkerboard Measurement

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Checkerboard Model

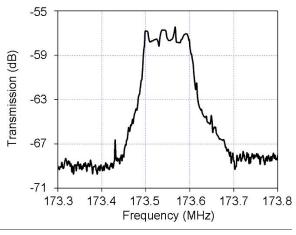
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S. Bhave, MEMS 05

Contributions

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Conclusion

- Built predictive model used to design checkerboard
- Used model reduction to get thousand-fold speedup
 - fast enough for interactive use

Outline

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Damping and Q

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Designers want high quality of resonance (Q)

Dimensionless damping in a one-dof system

$$\frac{d^2u}{dt^2} + Q^{-1}\frac{du}{dt} + u = F(t)$$

• For a resonant mode with frequency $\omega \in \mathbb{C}$:

$$Q := \frac{|\omega|}{2\operatorname{Im}(\omega)} = \frac{\operatorname{Stored\ energy}}{\operatorname{Energy\ loss\ per\ radian}}$$

Enter HiQLab

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HiQLab

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Conclusions

- Existing codes do not compute quality factors
- ... and awkward to prototype new solvers
- ... and awkward to programmatically define meshes
- So I wrote a new finite element code: HiQLab

Heritage of HiQLab

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SUGAR: SPICE for the MEMS world

- System-level simulation using modified nodal analysis
- Flexible device description language
- C core with MATLAB interfaces and numerical routines

FEAPMEX: MATLAB + a finite element code

- MATLAB interfaces for steering, testing solvers, running parameter studies
- Time-tested finite element architecture
- But old F77, brittle in places

Other Ingredients

CAD for MEMS

HiQLab

"Lesser artists borrow. Great artists steal."

– Picasso, Dali, Stravinsky?

- Lua: www.lua.org
 - Evolved from simulator data languages (DEL and SOL)
 - Pascal-like syntax fits on one page; complete language description is 21 pages
 - Fast, freely available, widely used in game design
- MATLAB: www.mathworks.com
 - "The Language of Technical Computing"
 - Good sparse matrix support
 - Star-P: http://www.interactivesupercomputing.com/
- Standard numerical libraries: ARPACK, UMFPACK



HiQLab Structure

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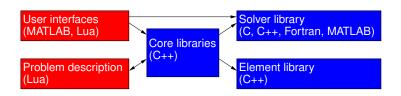
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Conclusion



- Standard finite element structures + some new ideas
- Full scripting language for mesh input
- Callbacks for boundary conditions, material properties
- MATLAB interface for quick algorithm prototyping
- Cross-language bindings are automatically generated

HiQLab's Hello World

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Conclusions

HiQLab's Hello World

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```
3 2 1 0 2 4 6 8 10 12
```

```
>> mesh = Mesh_load('beammesh.lua');
>> [M,K] = Mesh_assemble_mk(mesh);
>> [V,D] = eigs(K,M, 5, 'sm');
>> opt.axequal = 1; opt.deform = 1;
>> Mesh_scale_u(mesh, V(:,1), 2, 1e-6);
>> plotfield2d(mesh, opt);
```

Contributions

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Conclusion

- Wrote a new code, HiQLab, to study damping
- HiQLab is based on my earlier simulators:
 - SUGAR, for system-level MEMS simulation
 - FEAPMEX, for scripting parameter studies

Outline

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HIQLab

Losses Substrate modelin

1-D Example Finite Elements

Disk

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Example: Disk Resonator

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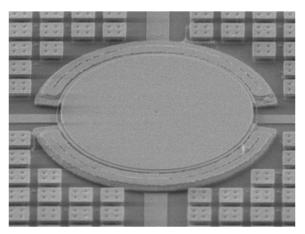
Losses

Substrate modeling 1-D Example

Disk

Resonator Analysis

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SiGe disk resonators built by E. Quévy

Damping Mechanisms

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LOSSES Substrate modeling

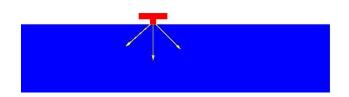
1-D Example

Finite Elements

Resonato Analysis

Conclusion

Backup Slide:



Possible loss mechanisms:

- Fluid damping
- Material losses
- Thermoelastic damping
- Anchor loss

Model substrate as semi-infinite with a

Perfectly Matched Layer (PML).



Perfectly Matched Layers

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LOSSES Substrate modeling

1-D Example Finite Elements

Disk Resonat Analysis

Conclusion

- Complex coordinate transformation
- Generates a "perfectly matched" absorbing layer
- Idea works with general linear wave equations
 - Electromagnetics (Berengér, 1994)
 - Quantum mechanics exterior complex scaling (Simon, 1979)
 - Elasticity in standard finite element framework (Basu and Chopra, 2003)

Model Problem

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Losses
Substrate mode

1-D Example

Disk Resonator

Conclusion

Backup Slides

• Domain: $x \in [0, \infty)$

Governing eq:

$$\frac{\partial^2 u}{\partial x^2} - \frac{1}{c^2} \frac{\partial^2 u}{\partial t^2} = 0$$

Fourier transform:

$$\frac{d^2\hat{u}}{dx^2} + k^2\hat{u} = 0$$

Solution:

$$\hat{u} = c_{\text{out}}e^{-ikx} + c_{\text{in}}e^{ikx}$$

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Anchor Losses

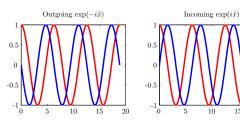
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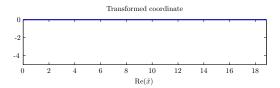
1-D Example

Finite Elemen

Resonator

Conclusion





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Anchor Losses

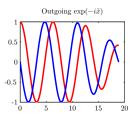
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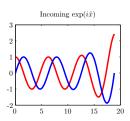
1-D Example

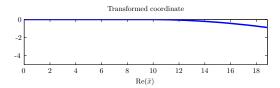
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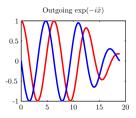
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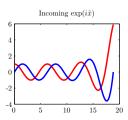
1-D Example

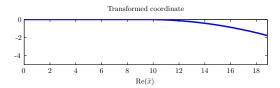
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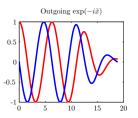
1-D Example

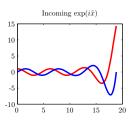
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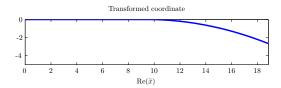
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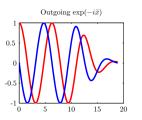
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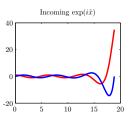
1-D Example

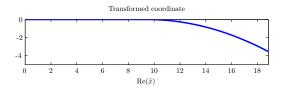
1-D Example

Disk

Analysis







Model Problem Illustrated

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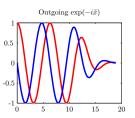
Losses

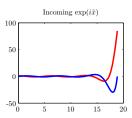
1-D Example

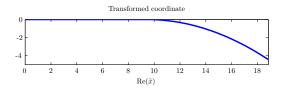
Finite Elemen

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Finite Element Implementation

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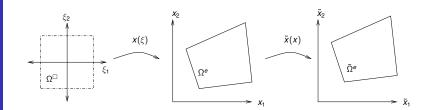
Substrate modeling

Finite Elements

Disk Resonator

Conclusion

Backup Slides



Combine PML and isoparametric mappings

$$\begin{array}{lll} \mathbf{k}^e & = & \int_{\Omega^\square} \tilde{\mathbf{B}}^T \mathbf{D} \tilde{\mathbf{B}} \tilde{J} \, d\Omega^\square \\ \\ \mathbf{m}^e & = & \int_{\Omega^\square} \rho \mathbf{N}^T \mathbf{N} \tilde{J} \, d\Omega^\square \end{array}$$

Matrices are complex symmetric



Contributions

CAD for MEMS

Resonar MEMS

ПіQLаі

Substrate modeling
1-D Example
Finite Flements

Disk Resonator

Conclusions

- New formulation of perfectly matched layers
 - Easy to apply PML to axisymmetric, 2D, or 3D models
 - Same formulation applies to electromagnetics, etc.
- Analysis of discretization error for PMLs
 - Results in cheap, automatic parameter optimization
- Structure-preserving model reduction for complex symmetric systems
 - Double accuracy for same work as standard method

Outline

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Conclusion

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Disk Resonator Simulations

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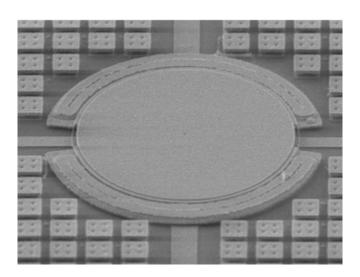
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Conclusion



Disk Resonator Mesh

CAD for MEMS

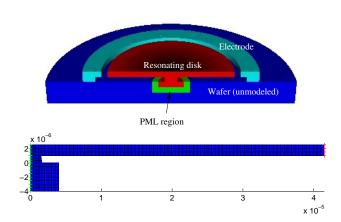
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Conclusio



- Axisymmetric model with bicubic mesh
- About 10K nodal points in converged calculation



Mesh Convergence

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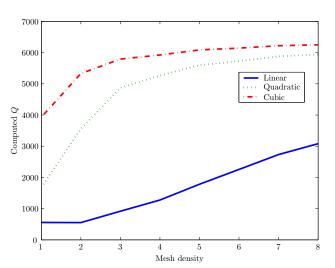
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Cubic elements converge with reasonable mesh density



Response of the Disk Resonator

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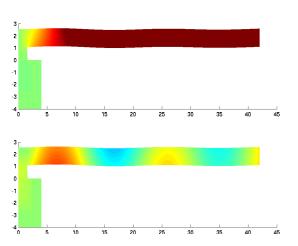
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Conclusion



Variation in Quality of Resonance

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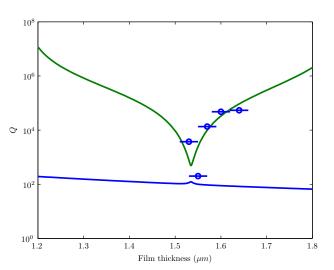
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Conclusion



Simulation and lab measurements vs. disk thickness

Explanation of Q Variation

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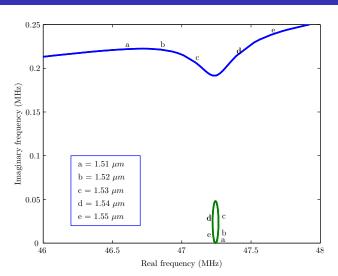
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Conclusio

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Interaction of two nearby eigenmodes



Contributions

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Disk Resonator Analysis

Conclusions

- Built disk model in HiQLab and verified against lab measurements
- Demonstrated dominance of anchor loss for this device
- Predicted geometric sensitivity of quality factor Q (which was subsequently verified in the lab)
- Explained Q sensitivity in terms of mode interference

Contributions Summary (1)

CAD for **MFMS**

Conclusions

- Application modeling
 - Finite element models of several devices
 - Discovery of effects of mode interference
 - Importance of anchor loss vs thermoelastic damping
- Mathematical analysis
 - Reformulation of perfectly-matched layers
 - Analysis of discretization and parameter choice in PMLs
 - Complex symmetry-preserving model reduction
 - Perturbation solution for thermoelastic damping
- Software: HiQLab, FEAPMEX, SUGAR

Contributions Summary (2)

CAD for MEMS

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Resonator Analysis Conclusions

Conordation

- HiQLab (about 33000 lines of code)
 - Collaborations at Berkeley, Cornell, Stanford, Bosch
- FEAPMEX (about 5000 lines of code)
 - 2400+ page views
 - Used for instrument models, stochastic structural analysis, ultrasonic nondestructive evaluation problems, material parameter identification problems
- SUGAR (about 18000 lines of code)
 - 2000+ downloads
 - Used in classes at Berkeley, Cornell, Johns Hopkins
 - Continued research use for design optimization

Other Contributions

CAD for MEMS

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HiQLa

Losses

Disk Resonato Analysis

Conclusions

- Lowered complexity of roots from $O(n^3)$ to $O(n^2)$
 - Code to go into next LAPACK release
- Developed first sparse subspace continuation code
 - Going into the next Matcont release
- Developed new network tomography method
- Designed initial security model for OceanStore
- Served as IEEE 754R secretary
- Responsible for last CLAPACK version

Future Work

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Losses

Disk Resonato Analysis

Conclusions

- Code development
 - Structural elements and elements for different physics
 - Design and implementation of parallelized version
- Theoretical analysis
 - More damping mechanisms
 - Sensitivity analysis and variational model reduction
- Application collaborations
 - Use of nonlinear effects (quasi-static and dynamic)
 - New designs (e.g. internal dielectric drives)
 - Continued experimental comparisons

Conclusions

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Conclusions

Backup Slide

RF MEMS are a great source of problems

- Interesting applications
- Interesting physics (and not altogether understood)
- Interesting numerical mathematics

http://www.cs.berkeley.edu/~dbindel

Application: Network monitoring

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Disk

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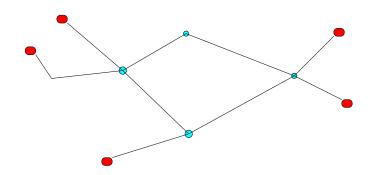
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Network tomography
PML model problem
Complex Symmetry

MEMS Fabrication
SUGAR and HiQLab
Elastic PMLs
Reflection Analysis

Reflection Analysis TED Subspace

Subspace Continuatio



- Set of n hosts in a large network
- n(n-1) directed paths between them
- Want latency and packet loss rates for each path
- Use info to choose servers, route around faults



Network "distance" metrics

CAD for MEMS

Linear relation between path length y_{ij} and link length x_i :

$$y_{ij} = \sum_{l \in \text{path}} x_l = \sum_l g_{ijl} x_l$$

where g_{ijl} indicates if link l is used on path $i \rightarrow j$. Write in matrix form (one path per row): y = Gx.

Examples:

- Latency
- Log probability of transmission success
- Jitter (variance in latency)

Resonan

HiQLa

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Network tomography
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Damping

SUGAR and HiQLai Elastic PMLs Reflection Analysis TED

Subspace Continuation

Path dependencies

CAD for **MEMS**

Network tomography

$$(A_i \rightarrow B_i) = (A_1 \rightarrow B_i) + (A_i \rightarrow B_1) - (A_1 \rightarrow B_1)$$

- Many linear dependencies among paths!
- $k := \operatorname{rank}(G) \ll n^2$
- Measure only k paths to infer properties for all paths

Rank of G: Lucent scan (bound)

original measurement regression on n regression on nlogn regressino on n^{1.25}

x 10⁴

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Losses

Resonato Analysis

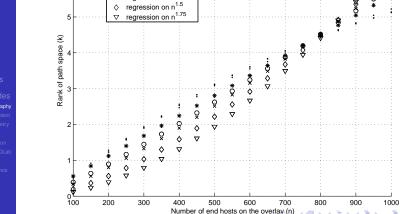
onclusion

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Subspace Continuation



Rank of G: AS-level Albert-Barabasi

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8000

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HiQLa

Losses

Resonato Analysis

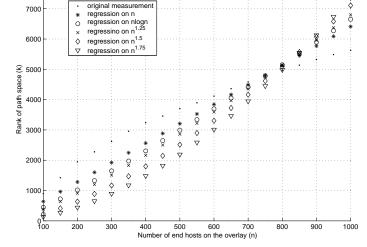
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Rank of G: AS Barabasi + RT Waxman

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Losses

Resonate Analysis

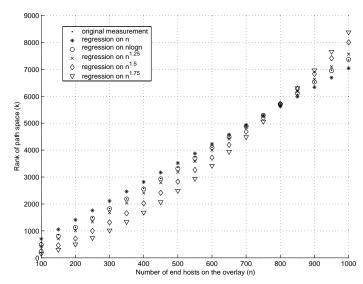
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Contributions

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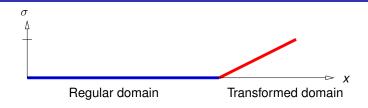
Reflection Analys

- Accurate predictions on $O(n^2)$ paths from a small number of measurements
- Prototype monitoring system on PlanetLab
- Ongoing work on fault diagnosis using similar ideas
- See: http://list.cs.northwestern.edu/

Model with Perfectly Matched Layer

CAD for **MEMS**

PML model problem



$$rac{d ilde{x}}{dx} = \lambda(x) ext{ where } \lambda(s) = 1 - i\sigma(s)$$

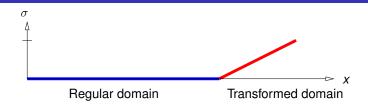
$$rac{d^2\hat{u}}{d ilde{x}^2} + k^2\hat{u} = 0$$

$$\hat{u} = c_{\mathrm{out}}e^{-ik ilde{x}} + c_{\mathrm{in}}e^{ik ilde{x}}$$

Model with Perfectly Matched Layer

CAD for **MEMS**

PML model problem



$$\frac{d\tilde{x}}{dx} = \lambda(x) \text{ where } \lambda(s) = 1 - i\sigma(s),$$

$$\frac{1}{\lambda} \frac{d}{dx} \left(\frac{1}{\lambda} \frac{d\hat{u}}{dx} \right) + k^2 \hat{u} = 0$$

$$\hat{u} = c_{\text{out}}e^{-ikx-k\Sigma(x)} + c_{\text{in}}e^{ikx+k\Sigma(x)}$$

$$\Sigma(x) = \int_0^x \sigma(s) \, ds$$

Model with Perfectly Matched Layer

CAD for MEMS

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Resonato Analysis

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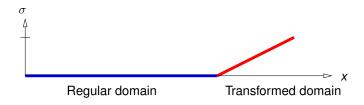
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Reflection Analysi TED

Subspace Continuation



If solution clamped at x = L then

$$rac{\emph{c}_{ ext{in}}}{\emph{c}_{ ext{out}}} = \emph{O}(\emph{e}^{-\emph{k}\gamma}) ext{ where } \gamma = \Sigma(\emph{L}) = \int_0^\emph{L} \sigma(\emph{s}) \, \emph{ds}$$

Eigenvalues and Model Reduction

CAD for **MFMS**

Want to know about the transfer function $H(\omega)$:

$$H(\omega) = p^{\mathsf{T}}(K - \omega^2 M)^{-1} b$$

Can either

- Locate poles of H (eigenvalues of (K, M))
- Plot H in a frequency range (Bode plot)

Usual tactic: subspace projection

- Build an Arnoldi basis V
- Compute with much smaller V*KV and V*MV

Can we do better?

Complex Symmetry

Variational Principles

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- Variational form for complex symmetric eigenproblems:
 - Hermitian (Rayleigh quotient):

$$\rho(\mathbf{v}) = \frac{\mathbf{v}^* \mathbf{K} \mathbf{v}}{\mathbf{v}^* \mathbf{M} \mathbf{v}}$$

Complex symmetric (modified Rayleigh quotient):

$$\theta(v) = \frac{v^T K v}{v^T M v}$$

- Key: relation between left and right eigenvectors.

Accurate Model Reduction

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SUGAR and HiQLa Elastic PMLs Reflection Analysis TED Build new projection basis from V:

$$W = \operatorname{orth}[\operatorname{Re}(V), \operatorname{Im}(V)]$$

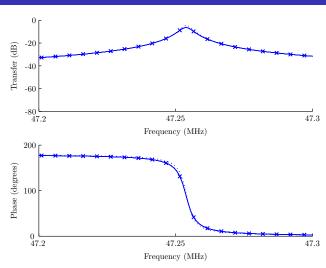
- span(W) contains both \mathcal{K}_n and $\bar{\mathcal{K}}_n$ \Longrightarrow double digits correct vs. projection with V
- W is a real-valued basis
 - ⇒ projected system is complex symmetric

Model Reduction Accuracy

CAD for **MEMS**

Complex Symmetry





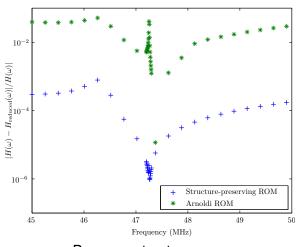
Results from ROM (solid and dotted lines) near indistinguishable from full model (crosses)

Model Reduction Accuracy

CAD for **MEMS**

Complex Symmetry

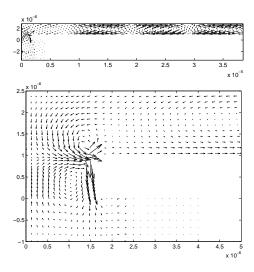
Preserve structure ⇒ get twice the correct digits



Time-Averaged Energy Flux

CAD for **MEMS**

Complex Symmetry



Sources of Damping

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Fluid damping

- \bullet Air is a viscous fluid (Re \ll 1)
- Can operate in a vacuum
- Shown not to dominate in many RF designs
- Material losses
 - Low intrinsic losses in silicon, diamond, germanium
 - Terrible material losses in metals
- Thermoelastic damping
 - Volume changes induce temperature change
 - Diffusion of heat leads to mechanical loss
- Anchor loss
 - Elastic waves radiate from structure

Sources of Damping

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Fluid damping

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Fabrication Outline

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Subspace Continuatio



- Si wafer
- ② Deposit 2 microns SiO2
- Pattern and etch SiO2 layer
- Deposit 2 microns polycrystalline S
- Pattern and etch Si layer
- Release etch remaining SiO2

Fabrication Outline

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Reflection Analysis TED Subspace



- Si wafer
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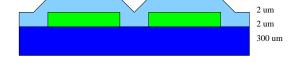


- Si wafer
- Deposit 2 microns SiO2
- Pattern and etch SiO2 layer
- Deposit 2 microns polycrystalline Si
- Pattern and etch Si layer
- Release etch remaining SiO2



CAD for **MFMS**

MEMS Fabrication



- Si wafer
- Deposit 2 microns SiO2
- Pattern and etch SiO2 layer
- Deposit 2 microns polycrystalline Si



CAD for MEMS

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HIQLa

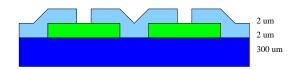
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MEMS Fabrication SUGAR and HiQLab Elastic PMLs



- Si wafer
- ② Deposit 2 microns SiO2
- Pattern and etch SiO2 layer
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- Pattern and etch Si layer
- Release etch remaining SiO2

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- Si wafer
- Deposit 2 microns SiO2
- Pattern and etch SiO2 layer
- Deposit 2 microns polycrystalline Si
- Pattern and etch Si layer
- Release etch remaining SiO2

Fabrication Result

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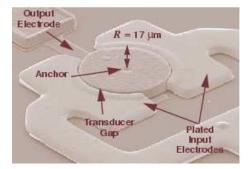
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TED Subspace Continuation





(C. Nguyen, iMEMS 02)

Role of simulation

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HiQLab: Modeling RF MEMS

- Explore fundamental device physics
 - Particularly details of damping
- Detailed finite element modeling
- Reduced models eventually to go into SUGAR

SUGAR: "Be SPICE to the MEMS world"

- Fast enough for early design stages
- Simple enough to attract users
- Support design, analysis, optimization, synthesis
- Verify models by comparison to measurement

Why simulate?

CAD for MEMS

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HIQLa

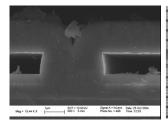
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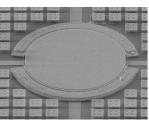
Resonato Analysis

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- "Build and break" is too expensive
 - Wafer processing costs months, thousands of dollars
 - Fabrication is imprecise
 - Days or weeks to take good measurements
- Good experiments need good hypotheses
- Even when device behavior is understood, still need to understand system behavior



From simulation to synthesis

CAD for MEMS

Resonal MEMS

HIQLa

Anchor

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Computer can assist at many levels:

- Fundamental physics
- Detailed device models
- System-level models and macromodels
- Metrology
- Design optimization
- Design synthesis

Research thrusts

CAD for **MFMS**

SUGAR and HiQl ab

- Model development (e.g. new finite elements)
- Numerical algorithms (e.g. model reduction)
- Numerical software engineering (SUGAR, HiQLab)
- Metrology and comparison to measurement
- Optimization and design synthesis

Research group

CAD for **MEMS**

SUGAR and HiQLab

		.	
Faculty		Students	
A. Agogino	(ME)	D. Bindel	(CS)
Z. Bai	(Math,CS,UCD)	J.V. Clark	(AS&T)
J. Demmel	(Math,CS)	C. Cobb	(ME)
S. Govindjee	(CEE)	D. Garmire	(CS)
R. Howe	(EE,ME)	T. Koyama	(CEE)
K.S.J. Pister	(EE)	J. Nie	(Math)
C. Sequin	(CS)	H. Wei	(CEE)
		Y. Zhang	(CEE)

SUGAR

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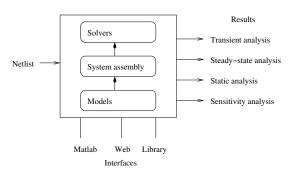
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MEMS Fabrication SUGAR and HiQLab Elastic PMLs

Reflection Analysi TED Subspace Goal: "Be SPICE to the MEMS world"

- Fast enough for early design stages
- Simple enough to attract users
- Support design, analysis, optimization, synthesis
- Verify models by comparison to measurement



SUGAR: Analysis of a micromirror

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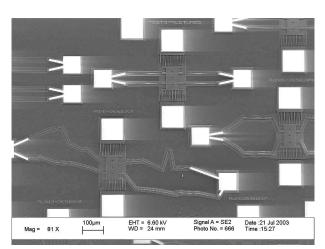
Aa 1 = 348.6 Deg $V 1 = 17.93 \mu m$ Aa R1

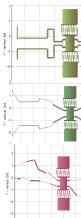
(Mirror design by M. Last)

SUGAR: Design synthesis

CAD for **MEMS**

SUGAR and HiQLab





SUGAR: Comparison to measurement

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MEMS Fabri

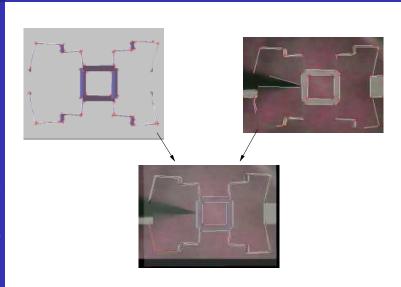
SUGAR and HiQLab

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$$\int_{\Omega} \epsilon(\mathbf{w}) : \mathbf{C} : \epsilon(\mathbf{u}) \, d\Omega - \omega^2 \int_{\Omega} \rho \mathbf{w} \cdot \mathbf{u} \, d\Omega = \int_{\Gamma} \mathbf{w} \cdot t_n d\Gamma$$
$$\epsilon(\mathbf{u}) = \left(\frac{\partial \mathbf{u}}{\partial \mathbf{x}}\right)^{s}$$

- Start from standard weak form
- Introduce transformed \tilde{x} with $\frac{\partial \tilde{x}}{\partial x} = \Lambda$
- Map back to reference system $(J_{\Lambda} = \det(\Lambda))$
- All terms are symmetric in w and ι

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SUGAR and H Elastic PMLs

$$\int_{\tilde{\Omega}} \tilde{\epsilon}(w) : C : \tilde{\epsilon}(u) d\tilde{\Omega} - \omega^{2} \int_{\tilde{\Omega}} \rho w \cdot u d\tilde{\Omega} = \int_{\Gamma} w \cdot t_{n} d\Gamma$$
$$\tilde{\epsilon}(u) = \left(\frac{\partial u}{\partial \tilde{x}}\right)^{s} = \left(\frac{\partial u}{\partial x} \Lambda^{-1}\right)^{s}$$

- Start from standard weak form
- Introduce transformed \tilde{x} with $\frac{\partial \tilde{x}}{\partial x} = \Lambda$
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SUGAR and HiC Elastic PMLs

$$\int_{\Omega} \tilde{\epsilon}(w) : C : \tilde{\epsilon}(u) J_{\Lambda} d\Omega - \omega^{2} \int_{\Omega} \rho w \cdot u J_{\Lambda} d\Omega = \int_{\Gamma} w \cdot t_{n} d\Gamma$$
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CAD for MEMS

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SUGAR and HiQ Elastic PMLs

$$\int_{\Omega} \tilde{\epsilon}(w) : \mathbf{C} : \tilde{\epsilon}(u) J_{\Lambda} d\Omega - \omega^{2} \int_{\Omega} \rho w \cdot u J_{\Lambda} d\Omega = \int_{\Gamma} w \cdot t_{n} d\Gamma$$
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- Map back to reference system $(J_{\Lambda} = \det(\Lambda))$
- All terms are symmetric in w and u

Continuum 2D model problem

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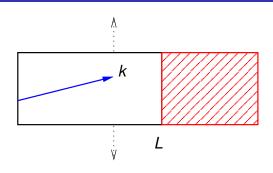
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Reflection Analysis

Subspace Continuation



$$\lambda(x) = \begin{cases} 1 - i\beta |x - L|^p, & x > L \\ 1 & x \le L. \end{cases}$$

$$\frac{1}{\lambda} \frac{\partial}{\partial x} \left(\frac{1}{\lambda} \frac{\partial u}{\partial x} \right) + \frac{\partial^2 u}{\partial y^2} + k^2 u = 0$$

Continuum 2D model problem

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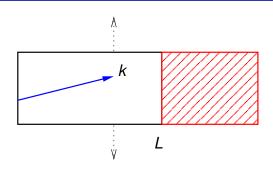
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$$\lambda(x) = \begin{cases} 1 - i\beta |x - L|^p, & x > L \\ 1 & x \le L. \end{cases}$$

$$\frac{1}{\lambda} \frac{\partial}{\partial x} \left(\frac{1}{\lambda} \frac{\partial u}{\partial x} \right) - k_y^2 u + k^2 u = 0$$

Continuum 2D model problem

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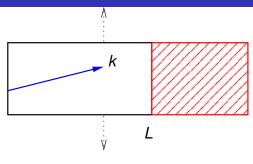
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$$\lambda(x) = \begin{cases} 1 - i\beta |x - L|^p, & x > L \\ 1 & x \le L. \end{cases}$$
$$\frac{1}{\lambda} \frac{\partial}{\partial x} \left(\frac{1}{\lambda} \frac{\partial u}{\partial x} \right) + k_x^2 u = 0$$

1D problem, reflection of $O(e^{-k_x\gamma})$



Discrete 2D model problem

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Anchor Losses

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Conclusion

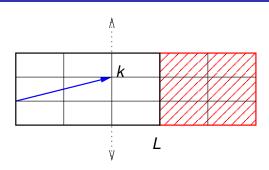
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PML model problem Complex Symmetry Damoing

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Reflection Analysis TED

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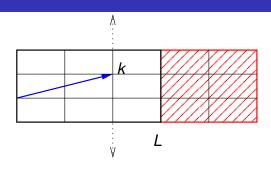
- Discrete Fourier transform in y
- Solve numerically in x
- Project solution onto infinite space traveling modes
- Extension of Collino and Monk (1998)



Nondimensionalization

CAD for **MEMS**

Reflection Analysis



$$\lambda(x) = \begin{cases} 1 - i\beta |x - L|^p, & x > L \\ 1 & x \le L. \end{cases}$$

Rate of stretching: ВhР

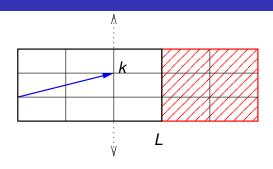
 $(k_x h)^{-1}$ and $(k_v h)^{-1}$ Elements per wave:

Elements through the PML:

Nondimensionalization

CAD for **MEMS**

Reflection Analysis



$$\lambda(x) = \begin{cases} 1 - i\beta |x - L|^p, & x > L \\ 1 & x \le L. \end{cases}$$

Rate of stretching: ВhР

 $(k_x h)^{-1}$ and $(k_v h)^{-1}$ Elements per wave:

Elements through the PML:

Discrete reflection behavior

CAD for MEMS

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HiQLa

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Conclusior

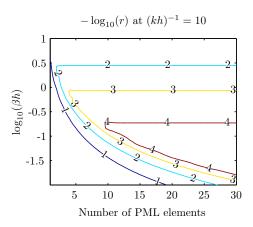
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Reflection Analysis

Subspace Continuation



Quadratic elements, p = 1, $(k_x h)^{-1} = 10$

Discrete reflection decomposition

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PML model problem Complex Symmetry

MEMS Fabrication SUGAR and HiQLa Elastic PMLs

Reflection Analysis

Subspace Continuatio

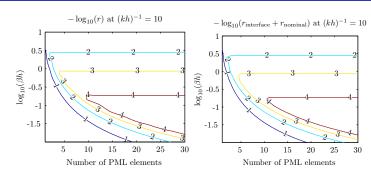
Model discrete reflection as two parts:

- Far-end reflection (clamping reflection)
 - Approximated well by continuum calculation
 - Grows as $(k_x h)^{-1}$ grows
- Interface reflection
 - Discrete effect: mesh does not resolve decay
 - Does not depend on N
 - Grows as $(k_x h)^{-1}$ shrinks

Discrete reflection behavior

CAD for **MEMS**

Reflection Analysis



Quadratic elements,
$$p = 1$$
, $(k_x h)^{-1} = 10$

- Model does well at predicting actual reflection
- Similar picture for other wavelengths, element types, stretch functions

Choosing PML parameters

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HiQLa

Losses

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Reflection Analysis

TED Subspace Continuation

- Discrete reflection dominated by
 - Interface reflection when k_x large
 - Far-end reflection when k_x small
- Heuristic for PML parameter choice
 - Choose an acceptable reflection level
 - Choose β based on interface reflection at k_{ν}^{max}
 - Chaosa longth based on far and reflection at N_{χ}
 - Choose length based on far-end reflection at k_x^{\min}

Thermoelastic damping (TED)

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u is displacement and $T = T_0 + \theta$ is temperature

$$\sigma = C\epsilon - \beta\theta \mathbf{1}$$

$$\rho u_{tt} = \nabla \cdot \sigma$$

$$\rho c_{V} \theta_{t} = \nabla \cdot (\kappa \nabla \theta) - \beta T_{0} \operatorname{tr}(\epsilon_{t})$$

- Volumetric strain rate drives energy transfer from mechanical to thermal domain
 - Irreversible diffusion ⇒ mechanical damping
 - Not often an important factor at the macro scale
 - Recognized source of damping in microresonators
- Zener: semi-analytical approximation for TED in beams
- We consider the fully coupled system

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Nondimensionalization

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Subspace

Subspace Continuation

$$\sigma = \hat{C}\epsilon - \xi\theta 1
u_{tt} = \nabla \cdot \sigma
\theta_t = \eta \nabla^2 \theta - \operatorname{tr}(\epsilon_t)$$

$$\xi := \left(\frac{\beta}{\rho c}\right)^2 \frac{T_0}{c_v} \text{ and } \eta := \frac{\kappa}{\rho c_v c L}$$

Length
$$\sim$$
 L Time \sim L/c , where $c=\sqrt{E/\rho}$ Temperature \sim $T_0 \frac{\beta}{\rho c_V}$

Scaling analysis

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$$\sigma = \hat{C}\epsilon - \xi\theta \mathbf{1}
u_{tt} = \nabla \cdot \sigma
\theta_t = \eta \nabla^2 \theta - \operatorname{tr}(\epsilon_t)$$

$$\xi := \left(\frac{\beta}{\rho c}\right)^2 \frac{T_0}{c_v} \text{ and } \eta := \frac{\kappa}{\rho c_v cL}$$

- Micron-scale poly-Si devices: ξ and η are $\sim 10^{-4}$.
- Small η leads to thermal boundary layers
- Linearize about $\xi = 0$

Discrete mode equations

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$$\sigma = \hat{C}\epsilon - \xi\theta 1
u_{tt} = \nabla \cdot \sigma
\theta_t = \eta \nabla^2 \theta - \operatorname{tr}(\epsilon_t)$$

$$\sigma = \hat{C}\epsilon - \xi\theta 1
-\omega^2 u = \nabla \cdot \sigma
i\omega\theta = \eta \nabla^2 \theta - i\omega \operatorname{tr}(\epsilon)$$

$$-\omega^2 M_{UU} U + K_{UU} U + K_{Ut} \theta = 0$$
$$i\omega D_{tt} \theta + K_{tt} \theta + i\omega D_{tu} U = 0$$

Perturbation computation

CAD for **MFMS**

$$-\omega^{2} M_{uu} u + K_{uu} u + K_{ut} \theta = 0$$

$$i\omega D_{tt} \theta + K_{tt} \theta + i\omega D_{tu} u = 0$$

Approximate ω by perturbation about $K_{ut} = 0$:

$$-\omega_0^2 M_{uu} u_0 + K_{uu} u_0 = 0$$

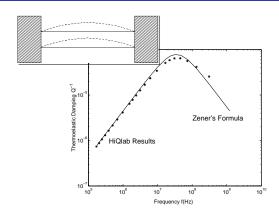
$$i\omega_0 D_{tt} \theta_0 + K_{tt} \theta_0 + i\omega_0 D_{tu} u_0 = 0$$

Choose $v: v^T u_0 \neq 0$ and compute

$$\begin{bmatrix} (-\omega_0^2 M_{uu} + K_{uu}) & -2\omega_0 M_{uu} u_0 \\ v^T & 0 \end{bmatrix} \begin{bmatrix} \delta u \\ \delta \omega \end{bmatrix} = \begin{bmatrix} -K_{ut} \theta_0 \\ 0 \end{bmatrix}$$

Comparison to Zener's model

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- Comparison of fully coupled simulation to Zener approximation over a range of frequencies
- Real and imaginary parts after first-order correction agree to about three digits with Arnoldi

Thermoelastic boundary layer

CAD for MEMS

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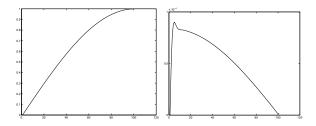
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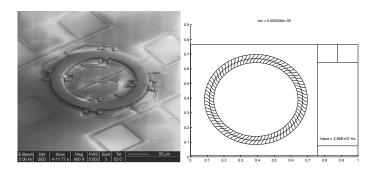


- One-dimensional test problem (longitudinal mode in a bar)
- Fixed temperature and displacement at left
- Free at right

Shear ring resonator

CAD for **MEMS**

Continuation



- Ring is driven in a shearing motion
- Can couple ring to other resonators
- How do we track the desired mode?

Mode tracking

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Conclusion:

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Subspace Continuation Find a continuous solution to

$$\left(K(s)-\omega(s)^2M(s)\right)u(s)=0.$$

- K and M are symmetric and M > 0
- Eigenvectors are M-orthogonal
- Perturbation theory gives good shifts
- Look if u(s+h) and u(s) are on the same path by looking at $u(s+h)^T M(s+h) u(s)$
- Many more subtleties in the nonsymmetric case
 - Focus of the CIS algorithm

Mode tracking in a shear resonator

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